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Topography evolution of rough-surface metallic substrates by solution deposition planarization method

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Highlights

- Topography evolution of metallic substrates coated with various numbers of amorphous oxide layers was investigated by atomic force microscopy in detail.
- On the electro-polished tapes, the surface smoothing was mainly due to the decrease of the depth at grain boundaries.
- On the mirror-rolled substrates, we found that both the frequencies and the amplitude of height fluctuations on the rolling marks were gradually reduced with increase of the coating numbers.

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